

SCREEN to establish an R&D center in Albany, New York for semiconductor production processes

Accelerating the development of world-leading wet processing technology

SCREEN Holdings Co., Ltd. is pleased to announce the establishment of a new research and development center, "SCREEN Advanced Technology Center of America, LLC" (hereinafter "ATCA"), in Albany, New York, with the aim of reinforcing its product competitiveness in the semiconductor production equipment business.



Albany NanoTech Complex which houses ATCA

High-resolution (300dpi) photo can be downloaded from www.screen.co.jp/en/about/nr-photo_2025

The newly established ATCA, in collaboration with NY Creates (New York Center for Research, Economic Advancement, Technology, Engineering and Science Corp), will be located within the state-of-the-art Albany NanoTech Complex, North America's most advanced non-profit semiconductor R&D center. ATCA will occupy 929 m² of clean room and 462 m² of office space.

With over 30% of all semiconductor manufacturing steps involving wet cleans, ATCA's presence within the Albany NanoTech ecosystem will enable SCREEN to accelerate development of next generation process applications including post etch, pre-deposition, pre-lithography, post CMP cleans, selective wet etch, and other critical process steps. These efforts will focus on performance, variability control, and sustainability, ensuring solutions meet the evolving needs for semiconductor device manufacturing.

In addition, ATCA will expand SCREEN's capacity and capability to engage with a broad range of industry stakeholders including, global customers, consortia, universities, technology and material suppliers, and the other globally recognized tenants of the Albany NanoTech Complex.

ATCA aims to accelerate elemental technology validation and equipment development not only in the wet processing field, where SCREEN is dominant, but also in emerging technology fields such as thermal processing and advanced packaging. This will enhance product competitiveness, increase added value, and support SCREEN's sustainability goals. ATCA will also collaborate with SCREEN's R&D base in Kyoto as well as the key Process Technology Center in Hikone, Japan, to facilitate innovation.

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SCREEN Holdings Co., Ltd.

We will continue our efforts to enhance corporate value, aiming to expand our presence in the semiconductor industry and thereby contribute to its further development.

| Overview of the company

Company name	SCREEN Advanced Technology Center of America, LLC (ATCA)
Location	201 Fuller Road, Suite 306, Albany, NY 12203
Representative	Ian Brown, PhD, President
Established	December 1, 2025

| Overview of the facility

Rented area	Clean room: 929 m ² Office space: 462 m ²
Main purpose	R&D for leading semiconductor production processes and equipment
Total investment	A total capital investment of around JPY 12.0 billion expected by fiscal year ending March 31, 2027, excluding other operating expenses

Related news release

SCREEN to Establish New Overseas Site to Reinforce Semiconductor Production Equipment Development

<https://www.screen.co.jp/en/news/NR250214-3E>